



1763

PATENT

Customer No. 22,852

Attorney Docket No. 08038.0048

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Nobuo ISHII

Serial No.: 09/776,675

Filed: February 6, 2001

For: MICROWAVE PLASMA
PROCESSING SYSTEM

Group Art Unit: 1763

Examiner: A. Crowell

#7B
1/6/03
MW

Assistant Commissioner for Patents

Washington, DC 20231

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Sir:

AMENDMENT

In reply to the Office Action dated October 3, 2002, please amend the application as follows:

IN THE CLAIMS:

Please amend claims 1, 8, and 17 as follows:

1. (Twice Amended) A microwave plasma processing system comprising:
 - a processing vessel;
 - B1* an antenna for introducing microwaves into said processing vessel, the antenna having a plurality of substantially ring-shaped and substantially concentric antenna waveguides, each of said antenna waveguides having a substantially rectangular radial cross-section and comprising a proximal end portion, a terminal end portion, and a wall having a plurality of slots formed at a predetermined interval;
 - a microwave supply source for supplying said microwaves to said antenna; and

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